



Docket No.: H0498.70130US01

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Tao Deng et al.  
Serial No.: 10/763,819  
Confirmation No.: 5026  
Filed: January 23, 2004  
For: FABRICATION OF METALLIC MICROSTRUCTURES VIA  
EXPOSURE OF PHOTSENSITIVE COMPOSITION  
Examiner: K. Duda  
Art Unit: 1756

**Certificate of Mailing Under 37 CFR 1.8(a)**

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as First Class Mail, in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Dated: 10/12/07

Melanie Chocero

**AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

In response to the Office Action dated June 29, 2007, please amend the above-identified U.S. patent application as follows:

**Amendments to the Specification** are reflected in the listing of claims which begins on page 2 of this paper.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 4 of this paper.

**Remarks/Arguments** begin on page 8 of this paper.